







- Superior image quality
- Enhaced NIR sensitivity
- Peltier cooling -20°C

Bigeye P

Low noise CCD camera, Peltier cooling, up to 11 MP

Bigeye P-132 NIR 搭载 Sony ICX285 传感器,在 1.3 MP 分辨率下速度可达 12.5 帧/秒。

The Bigeye is a low noise CCD camera. It satisfies even the highest expectations for excellent image quality. The peltier cooling provides a superior signal-to-noise ratio even with very long exposure times. Bigeye NIR camera versions are designed for applications which require sensitivity both in the visible spectrum and the NIR spectrum.

- Sensitive Sony and OnSemi sensors, up to 11 Megapixels
- Peltier cooling for long exposure times
- Superior signal/noise ratio
- Robust metal housing for industrial use
- GigE Vision



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接口 IEEE 802.3 1000baseT

分辨率 1280 (H) × 1024 (V)

传感器 Sony ICX285

传感器类型 CCD Progressive

传感器尺寸 Type 2/3

像元尺寸 6.45 μm × 6.45 μm

标准镜头接口 C-Mount

最大满帧帧率 12.5 fps

ADC 14 Bit

输出

Bit 位数 12-bit

黑白像素格式 Mono8, Mono10, Mono12

原始像素格式 BayerGB8, BayerGB10, BayerGB12

通用输入输出口 (GPIOs)

工作条件/尺寸

工作温度 0°C to +35°C

电源要求 (DC) 12 V

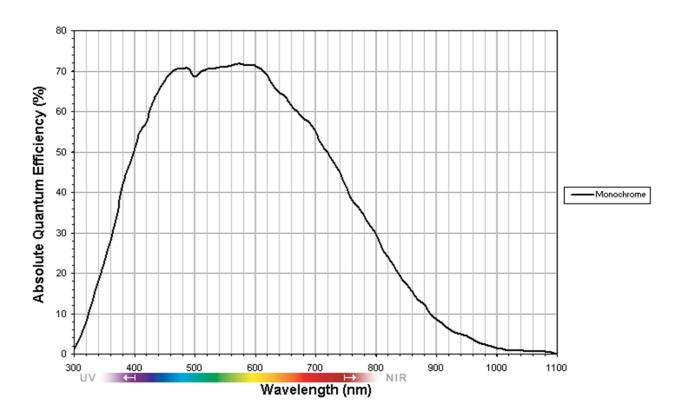
功耗 33.6 W @ 12 VDC

重量 1410 g

尺寸 (L×W×Hin mm) 111×90×99 (including connectors)



量子转换效率





特性

- Binning (2 x 2)
- Gain (6 dB)
- Exposure time 100 μs to 1000 seconds
- Background correction
- Continuous mode (image acquisition with maximum frame rate)
- Image on demand mode (triggered image acquisition)

In combination with Allied Vision's AcquireControl software, extensive image analysis functions are available:

- BCG LUT (brightness, contrast, gamma)
- Auto contrast
- Auto brightness
- Analyze multiple regions (rectangular, circle) within the image
- · Real-time statistics and histogram display



应用场景

The Bigeye P-132B NIR Cool is optimized for image acquisition both in the visible and in the NIR spectral range. For this reason, many applications can be realized with just one camera. Applications:

- Machine vision, visible and NIR spectrum
- Food inspection
- Medical and healthcare
- Microscopy
- Solar cell/wafer inspection, visible and NIR:
 - Glass inspection
 - Assembling inspection
 - Electroluminescence
 - Micro cracks detection
 - Defects
 - Efficiency